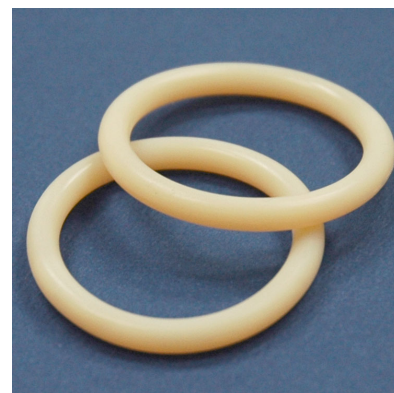


Technical Datasheet

High Temperature Perfluoroelastomer for Plasma Applications

Our XL Series is designed for performance excellence. XL12 is specially developed to handle the rigorous requirements of aggressive fluorine and oxygen based plasma while generating minimum particles. XL12 offers a high purity solution for both static and dynamic applications such as etch, remote plasma cleans and deposition.



Semiconductor Applications

- Deposition: CVD, APCVD,
- HDPCVD, RPCVD, SACVD
- Plasma Etch: oxide and metal
- Ashing
- Ion Implant
- Etch

Applications:

- Chamber Lid Seals
- Door Seals
- End Point Windows
- Gas Inlet Seals
- Isolator Valve Seals
- Slit Valves
- Window Seals

Typical Physical Properties

Color	Off-white	
PROPERTIES	ASTM	VALUE
Hardness, (Shore A)	D2240	78 -/+5
Tensile Strength psi, (MPa), min	D1414	2474 (17.06)
Elongation, %, min **	D1414	200
Modulus at 100% psi, (MPa), min	D1414	985 (6.79)
Compression Set, 72 Hrs@ 175°C	D395, Method B	27.2
Minimum Operating Temperature	-20°C	
Maximum Operating Temperature	260°C	

****EVEN THOUGH ELONGATION PROPERTY IS INDICATED, MOST PERFLUOROELASTOMER MATERIALS SHOULD NOT BE STRETCHED FOR OPTIMAL PERFORMANCE.**

Note: color variations may be observed in parts. Variations are considered to be cosmetic and inherent as a result of curing process, not indicative for foreign matter and is not expected to have an adverse effect on the performance of the part in service.



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